

- a. Electric generator means connected to a first multitude of electrodes of a multi-point probe;
 - b. A second multitude of switched impedance detection elements connecting said first multitude of electrodes of said multi-point probe; and
 - c. Electrical detector means for detecting a measuring signal from the electrical signal across said second multitude of switched impedance detection elements.
2. (Original) An electrical feedback detection system for detecting electrical contact of a multi-point probe to a electrically conducting material surface according to claim 1 further comprising an electrical connection between said electric generator means to said material test sample surface.
3. (Currently amended) An electrical feedback detection system for detecting electrical contact of a multi-point probe to a electrically conducting material surface according to claim 1-2 in which the electric generator means is a differential voltage to current converter comprising:
 - a. A precision amplifier providing two differential inputs, one output, and one reference input;
 - b. A precision resistive element providing an internal and external port, said internal port connected to said output of said precision amplifier, and;
 - c. A voltage follower providing an input and an output, said input connected to said external port of said precision resistive element, and said output connected to said reference input of said precision amplifier.

4. (Currently amended) An electrical feedback detection system for detecting electrical contact of a multi-point probe to an electrically conducting material test sample surface according to claim 1-3, further comprising a filter for filtering the output of said electrical detector means, comprising a low-pass filter, high-pass filter, band-pass filter, comparator filter or any combinations thereof.
5. (Currently amended) An electrical feedback detection system for detecting electrical contact of a multi-point probe to an electrically conducting material test sample surface according to claim 1-4 in which said multi-point probe comprises:
 - a. A supporting body defining a first surface;
 - b. A first multitude of conductive probe arms each of said conductive probe arms defining a proximal end and a distal end being positioned in co-planar relationship with said first surface of said supporting body, and said conductive probe arms being connected to said supporting body at said proximal ends thereof and having said distal ends freely extending from said supporting body, giving individually flexible motion to said first multitude of conductive probe arms; and
 - c. Said conducting probe arms originating from a process of producing said multi-point probe including producing said conductive probe arms on supporting wafer body in facial contact with said supporting wafer body and removal of a part of said wafer body providing said supporting body and providing said conductive probe arms freely extending from said supporting body.